ROBOT FOR HANDLING WAFER CASSETTE

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- european:

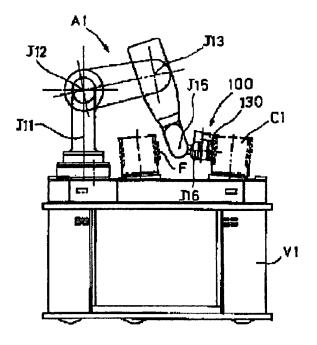
Application number:

JP19910192784 19910708

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Abstract of JP5146984

PURPOSE:To hold adjacent wafer cassettes having flanges on side face sides in succession with a simple action.
CONSTITUTION:In a wafer cassette handling robot having a hand 100 fitted rotatably by a rotary shaft J16 at the tip of an arm A1 provided with multiple joints and a pair of chuck sections 130 provided on the hand 100 to hold a semiconductor wafer cassette C1, a pair of chuck sections 130 are arranged point-symmetrically with the rotary shaft J16 as viewed from the axial direction of the rotary shaft 16.



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